



Attorney/Docket No. 34003.55
Customer No. 000027683

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Christof Baur, et al.

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Group Art Unit: Unknown

Serial No. 10/684,120

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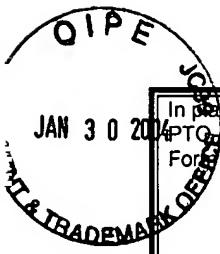
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In place of PTO-1449 Form 1449				U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	10/684,120		
SHEET	1	OF	1	Filing Date	October 10, 2003		
				Applicant(s)	Christof Baur, et al.		
				Art Unit	Unknown		
				Examiner Name	Unknown		
				Attorney Docket Number	34003.55		

OTHER PRIOR ART							
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume-issue number(s), publisher, city/country where published					
	AA	C. BAUR, A. BUGACOV, B.E. KOEL, A. MADHUKAR, N. MONTOYA, T.R. RAMACHANDRAN, A.A.R. REQUICHA, R. RESCH and P. WILL; <i>Nanoparticle manipulation by mechanical pushing: underlying phenomena and real-time monitoring</i> ; Nanotechnology 9 (1998) 360-364; August 7, 1998.					
	AB	T. NAKAYAMA, D.H. HUANG, M. AONO; <i>Extraction, deposition, and displacement of atoms by STM</i> ; Microelectronic Engineering 32 (1996) 191-201.					
	AC	P. MORIARTY, Y.R. MA, M.D. UPWARD, P.H. BETON; <i>Translation, rotation and removal of C₆₀ on Si(100) - 2 x 1 using anisotropic molecular manipulation</i> ; Surface Science 407 (1998) 27-35.					
	AD	John M. MICHELSSEN, Mark J. DYER, Jim VON EHR; <i>Assembler Construction by Proximal Probe</i> ; Paper presented at the 5 th Foresight Conference on Molecular Nanotechnology, Nov. 5-8, 1997, Palo Alto, CA.					
	AE	H. TANG, M.T. CUBERES, C. JOACHIM, J.K. GIMZEWSKI; <i>Fundamental considerations in the manipulation of a single C₆₀ molecule on a surface with an STM</i> ; Surface Science 386 (1997) 115-123.					
	AF	Jim GIMZEWSKI; <i>Atoms get a big push, or is that a pull?</i> Physics World, November 1997, pp. 27, 28.					
	AG	James K. GIMZEWSKI, Christian JOACHIM; <i>Nanoscale Science of Single Molecules Using Local Probes</i> ; Science Molecules Vol. 283; March 12, 1999; pp. 1683-1686.					
	AH	D. M. EIGLER, E.K. SCHWEIZER; <i>Positioning single atoms with a scanning tunnelling microscope</i> ; Letters to Nature Vol. 344, April 5, 1990; pp. 524-526.					
	AI	Michael R. FALVO, Richard SUPERFINE; <i>Mechanics and friction at the nanometer scale</i> ; Dept. of Physics and Astronomy, The University of North Carolina at Chapel Hill; pp. 1-17.					
	AJ	H.J. LEE, W. HO; <i>Single-Bond Formation and Characterization with a Scanning Tunneling Microscope</i> ; Science Reports Vol. 286; November 26, 1999; pp. 1719-1722.					
	AK	Seiji HEIKE, Tomihiro HASHIZUME, Yasuo WADA; <i>Nanoneedle formation on silicon (111) surface using a scanning tunneling microscope tip</i> ; J. Appl. Phys. 80 (7); October 1, 1996; pp. 4182-4188.					
	AL	D.H. HUANG, Y. YAMAMOTO; <i>Physical mechanism of hydrogen deposition from a scanning tunneling microscopy tip</i> ; Applied Physics A 64 (1997); pp. 419-422.					
	AM	J.W. LYDING, T.C. SHEN, J.S. HUBACEK, J.R. TUCKER, G.C. ABELN; <i>Nanoscale patterning and oxidation of H-passivated Si(100) - 2 x 1 surfaces with an ultrahigh vacuum scanning tunneling microscope</i> ; Appl. Phys. Lett. 64 (15); April 11, 1994; pp. 2010-2012.					
	AN	Dehuan HUANG, Hironaga UCHIDA; <i>Deposition and subsequent removal of single Si atoms on the Si(111) - 7 x 7 surface by a scanning tunneling microscope</i> ; J. Vac. Sci. Technol. B 12 (4); July/August 1994; pp. 2429-2433.					
	AO	D. CHEN, R.K. WORKMAN, D. SARID; <i>Adsorption and decomposition of C₆₀ molecules on Si(111) surfaces</i> ; J. Vac. Sci. Technol. B 14 (2), March/April 1996; pp. 979-981.					
	AP	P.H. BETON, A.W. DUNN, P. MORIARTY; <i>Manipulation of C₆₀ molecules on a Si surface</i> ; Appl. Phys. Lett. 67 (8); pp. 1075-1077; August 21, 1995					
	AQ	H. TAKASHIMA, M. NAKAYA, A. YAMAMOTO, A. HASHIMOTO; <i>Two-step growth of C₆₀ films on H-terminated Si (111) substrate</i> ; Journal of Crystal Growth 227-228 (2001), pp. 825-828					
	AR	F. OWMAN, P. MARTELSSON; <i>STM study of structural defects on in situ prepared Si(111) X 1-H surfaces</i> ; Surface Science 324 (1995), pp. 211-225					

Examiner Signature		Date Considered	
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.